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BOX PATENT APPLICATION

Assistant Commissioner for Patents
Washington, D.C. 20231

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RE: *U.S. Patent Application Entitled:*
IMPROVED DEPTH OF FOCUS (DOF) FOR TRENCH-FIRST-VIA-LAST
(TFVL) DAMASCENE PROCESSING WITH HARD MASK AND LOW
VISCOSITY PHOTORESIST
Inventor(s): Christian Zistl, Ting Yiu Tsui and Steven Keetai Park
Client Ref.: TT3851; Our Ref.: 2000.046600

Sir:

Transmitted herewith for filing are:

- (1) 27-page patent specification with 32 claims and an abstract (also Figures 1-6 on 3 sheets);
- (2) Declaration;
- (3) Power of Attorney; and
- (4) Assignment and Assignment Cover Sheet

All correspondence, notices, official letters and other communications should be directed Randall C. Furlong, Ph.D., Williams, Morgan & Amerson, P.C., 7676 Hillmont, Suite 250, Houston, TX 77040, and all telephone calls should be directed to Randall C. Furlong, Ph.D. at (713) 934-4061.

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Application for United States Letters Patent

for

**IMPROVED DEPTH OF FOCUS (DOF) FOR
TRENCH-FIRST-VIA-LAST (TFVL) DAMASCENE PROCESSING
WITH HARD MASK AND LOW VISCOSITY PHOTORESIST**

by

***Christian Zistl
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Steven Keetai Park***

EXPRESS MAIL MAILING LABEL

NUMBER *EL522492654US*
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